Secondary electron effects in low energy ion beams

# Daniel Noll

Institute for Applied Physics Goethe University Frankfurt am Main

Monday, March 11<sup>th</sup> 2013 HICforFAIR Workshop - Current Topics in Accelerator- and Plasmaphysics



Measurements ●○○	Sources of secondary electrons	The PIC code "Bender"	Simulation example	Conclusion ○
Measured	secondary electro	on effects		

"Satellites" in emittance measurements



<sup>&</sup>lt;sup>1</sup>Peter Groß. "Untersuchungen zum Emittanzwachstum intensiver Ionenstrahlen bei teilweise Kompensation der Raumladung". PhD thesis. Goethe Universität Frankfurt am Main, 2000

Measurements ○●○	Sources of secondary electrons	The PIC code "Bender"	Simulation example	Conclusion ○
Measured	secondary electro	on effects		

Beam potential



Figure: Setup used by P. Groß to measure space charge compensation<sup>1</sup>

<sup>&</sup>lt;sup>1</sup>Peter Groß. "Untersuchungen zum Emittanzwachstum intensiver Ionenstrahlen bei teilweise Kompensation der Raumladung". PhD thesis. Goethe Universität Frankfurt am Main, 2000



### Energy distribution of residual gas ions





Figure: Spectrum between the solenoids with partially compensated and decompensated beam<sup>1</sup>

Figure: Spectrum with emittance scanner inserted and retracted<sup>1</sup>

<sup>&</sup>lt;sup>1</sup>Peter Groß. "Untersuchungen zum Emittanzwachstum intensiver Ionenstrahlen bei teilweise Kompensation der Raumladung". PhD thesis. Goethe Universität Frankfurt am Main, 2000







- Depends on surface treatment
- Data for electrons available, for ions hard to find

<sup>&</sup>lt;sup>3</sup>Manfred von Ardenne. Tabellen zu Angewandten Physik Band 1. VEB Deutscher Verlag der Wissenschaften, 1973

<sup>&</sup>lt;sup>4</sup>MA Furman and MTF Pivi. "Probabilistic model for the simulation of secondary electron emission". In: *Phys. Rev. ST Accel. Beams* 5.124404 (2002), pp. 124404–1

Measurements	Sources of secondary electrons ○●	The PIC code "Bender" 0000	Simulation example	Conclusion ○
Sources	of secondary elect	rons		



e<sup>-</sup> on N<sub>2</sub>

Figure: Electron production cross section for protons on different residual gas ions [5]

Figure: Electron impact ionisation cross section for  $N_2$  [4]

Maximum on N<sub>2</sub>: 
$$\sigma_{
m {\it p}}\,(
m 50 keV) = 5.96\, {
m \AA^2}$$
,  $\sigma_{
m {\it e}}\,(
m 100 eV) = 2.62\, {
m \AA^2}$ 

Sources of secondary electrons The PIC code "Bender" Measurements Simulation example Conclusion

# Measured secondary electron effects

A lot of open questions...

#### "

Einige Erweiterungen, z. B. die Einbeziehung der Restgasionen in die Simulation, sind zwar schon vorgezeichnet und harren "lediglich" der Realisierung, das gravierendste Problem, die Beschreibung des kompensierten Strahles in Anwesenheit von magnetischen Feldern, erfordert jedoch noch weitergehende theroretische und experimentelle Untersuchungen. "

Dissertation P. Groß. 2000



Valid approximations for low-energy beams:

- Non-relativistic:  $\beta < 0.1, \gamma \approx 1$
- Electrostatic: self-magnetic field  $B_{Beam} \approx B_{Earth}$
- Grouping of particles to macroparticles "phase space sampling"



Measurements Sources of secondary electrons The PIC code "Bender" Simulation example Conclusion The Particle-in-Cell code "Bender" Conclusion Approximation of geometry on the grid

Finite difference discretization of the second derivatives with different stencil distances  $h_+$ ,  $h_-$ :

$$\frac{\mathrm{d}^{2}\varphi}{\mathrm{d}x^{2}}\left(x\right) = \frac{2}{h_{-}h}\varphi\left(x-h_{-}\right) + \frac{2}{h_{+}h}\varphi\left(x+h_{+}\right) - \frac{2}{h_{+}h_{-}}\varphi\left(x\right) + \mathcal{O}\left(h^{2}\right)$$



 Measurements
 Sources of secondary electrons
 The PIC code "Bender"
 Simulation example
 Conclusion

 000
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00
 00</td

- Gebunchte und kontinuierliche Strahlen
- Multi-Species
  - ۲



Measurements	Sources of secondary electrons	The PIC code "Bender" ○○○●	Simulation example	Conclusion O
Simulatic	on difficulties			

Limits on time step:

- $\frac{\Delta p}{p} \ll 1 \longrightarrow \Delta t \ll \frac{\sqrt{2mW}}{q|\vec{E}|}$ , i.e.  $\approx 480 \,\mathrm{ps}$  for  $10 \mathrm{eV} \,\mathrm{e^-}$  in 200 mA, 120 keV proton beam
- Cyclotron frequency:  $\omega = \frac{qB}{m}$ , stable numeric integration (velocity verlet algorithm) requires  $\Delta t \ll \frac{2}{\omega}$ , i.e.  $\approx 23 \text{ ps}$  in B = 500 mT

Measurements	Sources of secondary electrons	The PIC code "Bender" ○○○●	Simulation example	Conclusion O
Simulatio	n difficulties			

Limits on time step:

- $\frac{\Delta p}{p} \ll 1 \longrightarrow \Delta t \ll \frac{\sqrt{2mW}}{q|\vec{E}|}$ , i.e.  $\approx 480 \,\mathrm{ps}$  for  $10 \mathrm{eV} \,\mathrm{e^-}$  in 200 mA, 120 keV proton beam
- Cyclotron frequency:  $\omega = \frac{qB}{m}$ , stable numeric integration (velocity verlet algorithm) requires  $\Delta t \ll \frac{2}{\omega}$ , i.e.  $\approx 23 \text{ ps}$  in B = 500 mT

### Electron production on walls

- η > 1 in relevant energy range: high number of particles
- Limited data on secondary emission yield available

Measurements	Sources of secondary electrons	The PIC code "Bender" ○○○●	Simulation example	Conclusion O
Simulation difficulties				

Limits on time step:

- $\frac{\Delta p}{p} \ll 1 \longrightarrow \Delta t \ll \frac{\sqrt{2mW}}{q|\vec{E}|}$ , i.e.  $\approx 480 \,\mathrm{ps}$  for  $10 \mathrm{eV} \,\mathrm{e^-}$  in 200 mA, 120 keV proton beam
- Cyclotron frequency:  $\omega = \frac{qB}{m}$ , stable numeric integration (velocity verlet algorithm) requires  $\Delta t \ll \frac{2}{\omega}$ , i.e.  $\approx 23 \text{ ps}$  in B = 500 mT

### Electron production on walls

- η > 1 in relevant energy range: high number of particles
- Limited data on secondary emission yield available

## lonisation of residual gas

- Mean time between collisions ( $p = 10^{-7}$  mbar,  $W_b = 50$  keV): 2.2 s
- Influence on residual gas pressure?







$$\Delta T = 50 \,\mathrm{ps}, \ T = 5 \,\mathrm{\mu s}.$$

One electron per proton  $W_{\rm c}^{start} = 1 \, {\rm eV}$ 

$$\begin{split} I_b &= 100 \,\mathrm{mA} \\ W_b &= 120 \,\mathrm{keV} \\ \varphi_b^{max} &= 1090 \, V \\ U_{comp} &= -250 \ldots - 1500 \, V \end{split}$$

32 CPUs on CSC "Fuchs" Lattice  $80 \times 80 \times 400$ .  $h = 1.25 \,\mathrm{mm}$ 1.9 million dofs 1000 new particles per step, 3.7 million in flight











z [cm]





Measurements	Sources of secondary electrons	The PIC code "Bender"	Simulation example ○○○○○●○	Conclusion O
Electron	column oscillatio	า		



Measurements	Sources of secondary electrons	The PIC code "Bender"	Simulation example 000000●	Conclusion O
Influence	on the proton be	am		



Measurements	Sources of secondary electrons	The PIC code "Bender"	Simulation example	Conclusion ●
Conclusio	on and outlook			

- Secondary electrons have an effect on beam dynamics in the low energy section of an accelerator
- The Particle-in-cell method can be used to study these effects
- Systematic studies of the dependance of the equilibrium state and the rise time on the production rates
- Realistic models for electron production
  - Measurement of the SEY for different materials for different beam energies at the HTL test stand inclusion in the PIC code
  - $\bullet\,$  Include model from Furman and Pivi [2] for electron  $\leftrightarrow$  wall interaction
  - Interaction between electrons, ions  $\leftrightarrow$  residual gas dynamics of the residual gas?
- Space charge compensation in beam line components
- Simulation of real systems and comparison with measurements
  - FRANZ LEBT and  $E \times B$  chopper compensation of a pulsed proton beam
  - Gabor lenses focussing using a confined electron plasma